

**July 8–11, 2024**  
The University of Tokyo, Japan

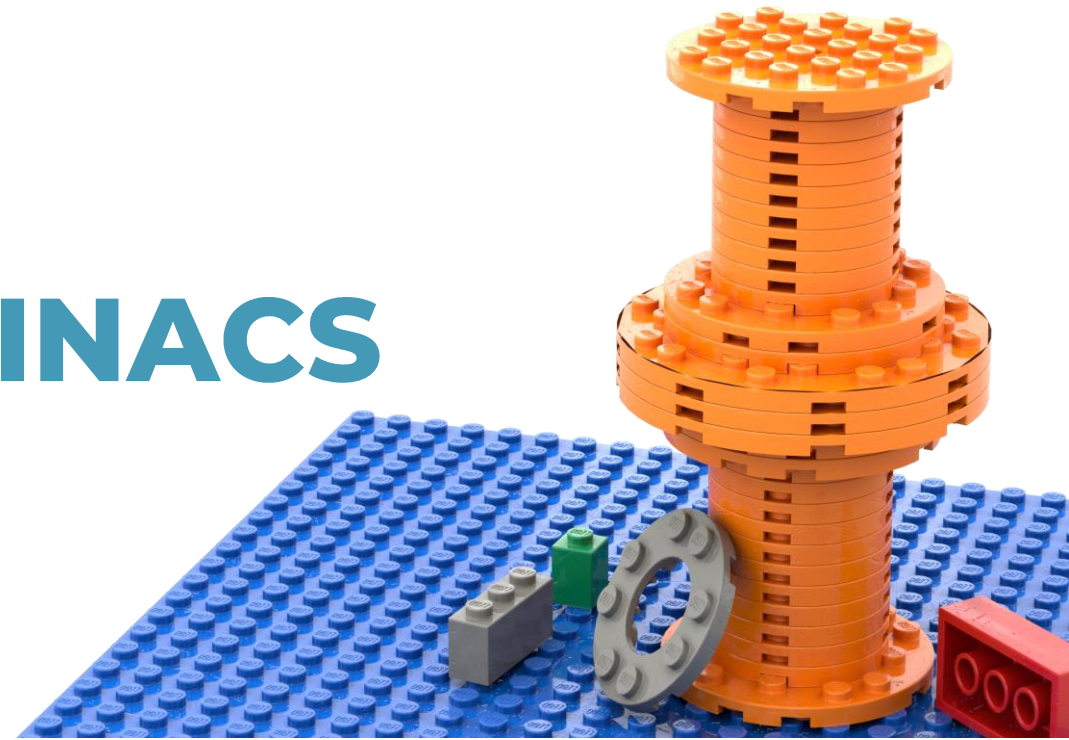
*Work supported by INFN CSN5 experiment SAMARA and INFN CSN1 experiments SRF and RD\_FCC*



*This project has received funding from the European Union's Horizon-INFRA-2023-TECH-01 under GA No 101131435 – iSAS and from the European Union's Horizon 2020 Research and Innovation programme under GA No 101004730 – I.FAST*



# **Nb<sub>3</sub>Sn on Cu thin film SRF cavities for new generation LINACS operating at 4.5 K**



# Key word: sustainability



European Union



United Nations



**Save energy**



**Reduce resources consumption and waste production**



**Clean and green procedures**

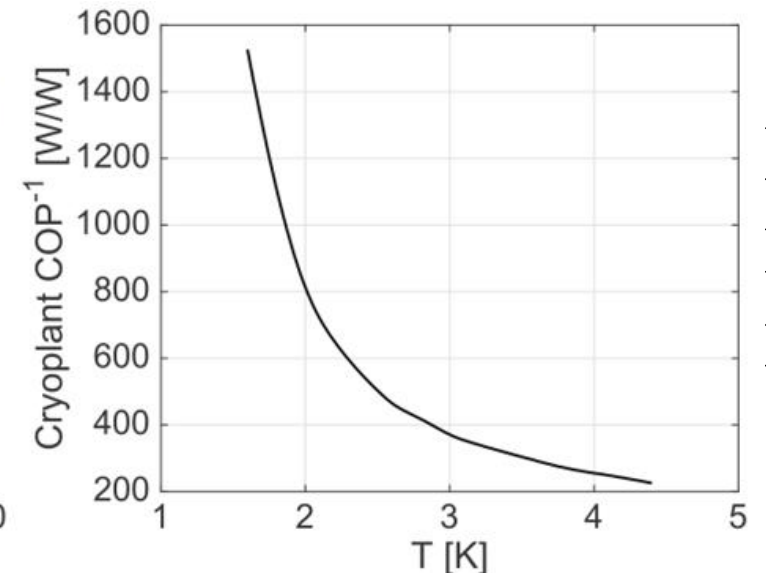
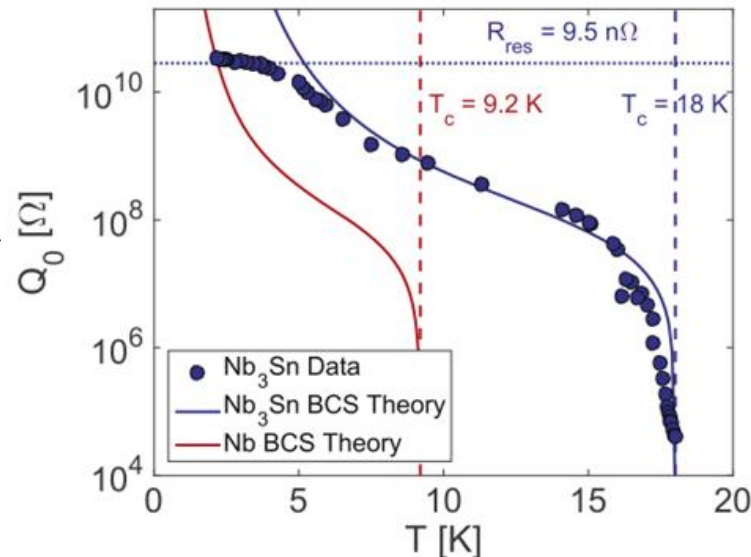
# Nb<sub>3</sub>Sn motivation

**Energy saving** is mandatory for the **next generation accelerators**

**Cryogenics** is one of the **larger energy cost** in modern SRF accelerators

➔ Move from **bulk Nb @2K** to **Nb<sub>3</sub>Sn @4.5 K**  
reduces cryogenic power by a factor of 3

7.5 GeV LINAC new construction

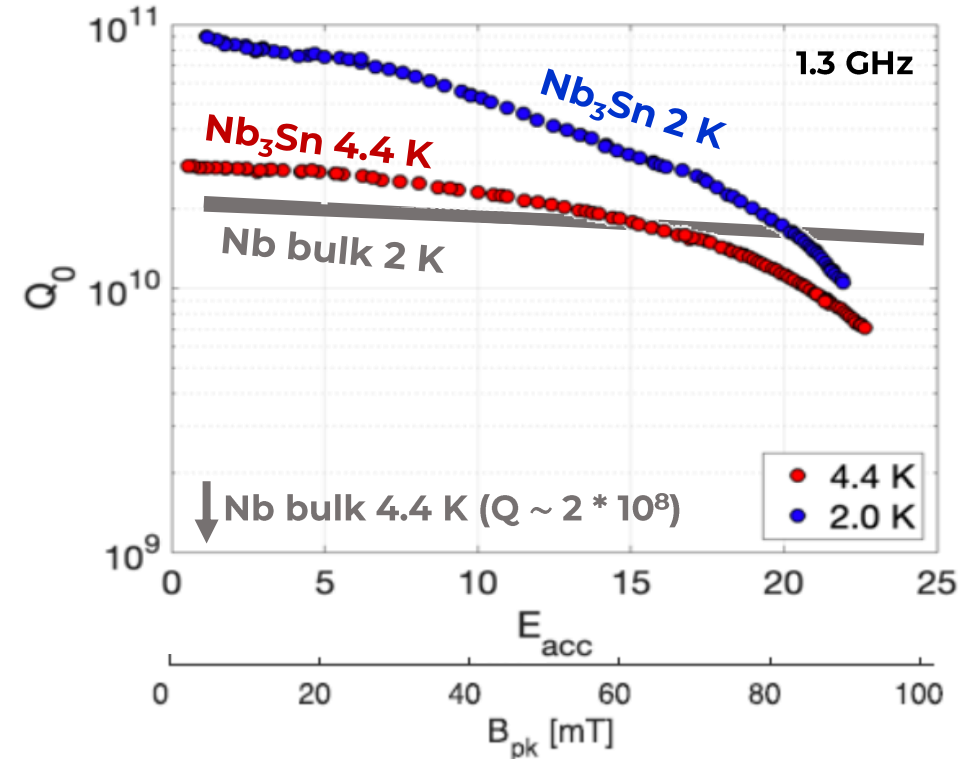
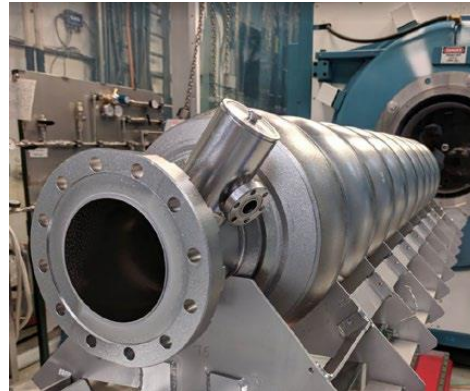
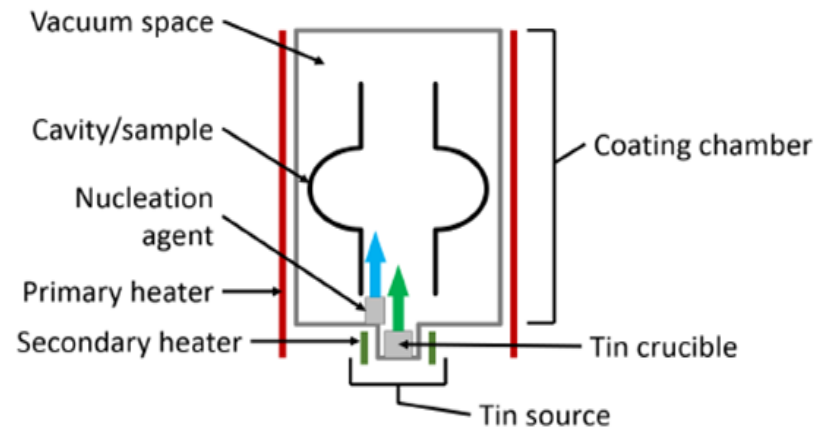


Supercond. Sci. Technol. 30 (2017) 033004

# Nb<sub>3</sub>Sn state of the art

## Vapor Tin Diffusion

Cornell, Fermilab, JLab, KEK



S. Posen, SRF 2019 proceedings (elaborated)

## Technology limitation:

- ▶ **Reproducibility**
- ▶ **Nb as Substrate** (expensive, chemistry, no interlayer possible)

# A different approach: Nb<sub>3</sub>Sn on Cu



## Cu substrate as several advantages:

- ▶ **Cheaper** than Nb
- ▶ Higher **thermal conductivity**
- ▶ Higher **mechanical stability**
- ▶ **PVD technology** (Nb on Cu) already used for LEP, LHC, HIE-ISOLDE @ CERN  
ALPI @ INFN LNL



# Nb<sub>3</sub>Sn on Cu: Multiple challenges

- ▶ A15 are Brittle materials
- ▶ Complicated Phase Diagram
- ▶ Low melting point substrate
- ▶ Interface diffusion
- ▶ Coating Parameters
- ▶ Substrate preparation
- ▶ Target Production/Magnetron Design
- ▶ Trapped Flux
- ▶ Tuning



# Nb<sub>3</sub>Sn on Cu: Multiple challenges

- ▶ Al5 are Brittle materials
- ▶ Complicated Phase Diagram
- ▶ Low melting point substrate
- ▶ **Interface diffusion**
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- ▶ **Tuning**

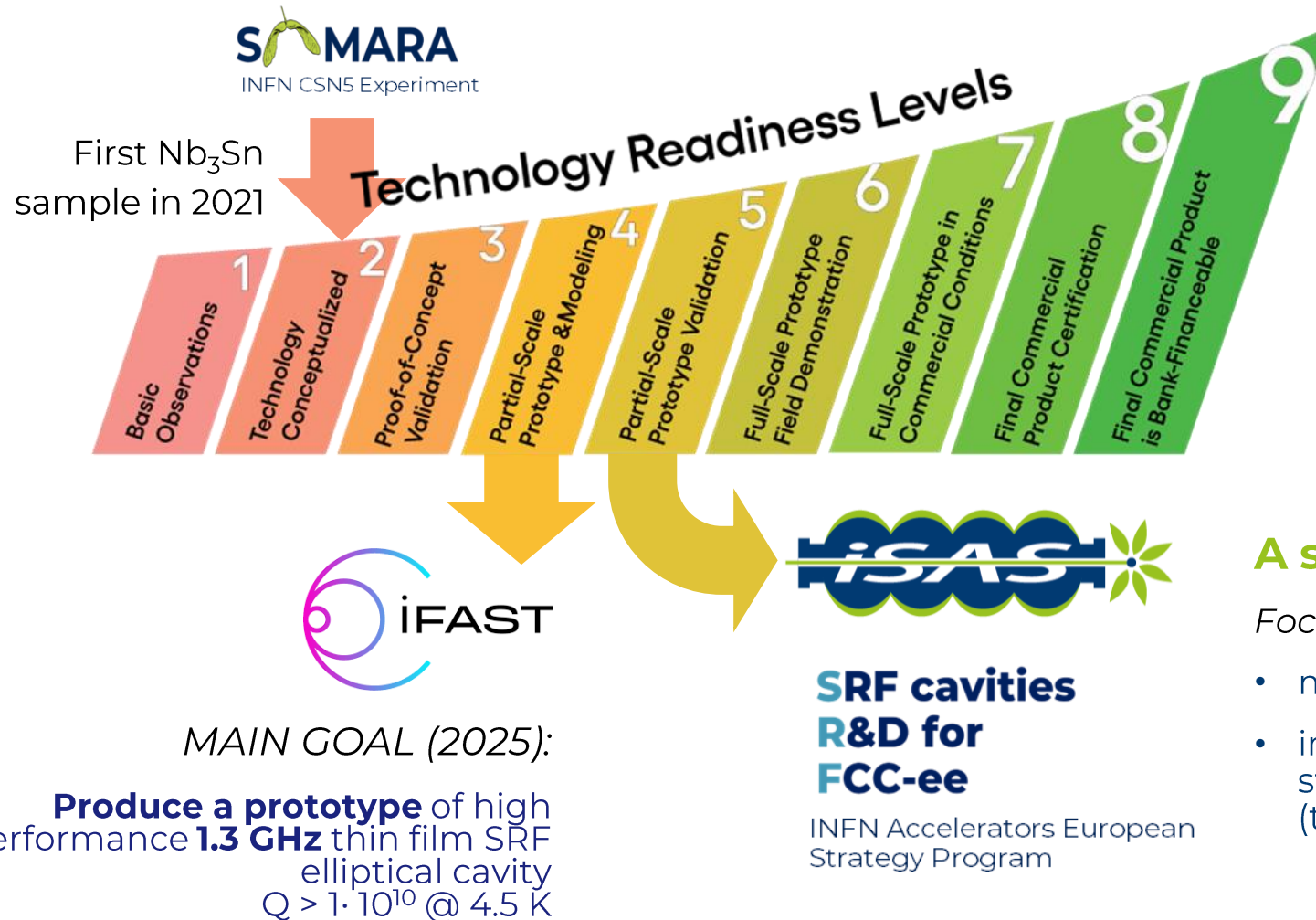


SRF cavities  
R&D for  
FCC-ee

INFN Accelerators European  
Strategy Program



# Nb<sub>3</sub>Sn on Cu TRL evolution @LNL





# I.FAST WP9 Collaboration



C. Pira, O. Azzolini, R. Caforio, E. Chyhyrynets, D. Fonnesu, D. Ford, V. Garcia, G. Keppel, G. Marconato, A. Salmaso, F. Stivanello (LNL)  
M. Bertucci, R. Paparella (LASA)



O.B. Malyshev, R. Valizadeh, C. Benjamin, T. Sian, L. Smith, D. Seal



C.Z. Antoine, S. Berry, Y. Kalboussi, T. Proslie



D. Longuevergne, O. Hryhorenko,



S. Keckert, O. Kugeler, J. Knobloch



S. Prucnal, S. Zhou



X. Jiang, T. Staedler, A. Zbtsovskii



E. Seiler, R. Ries



A. Medvids, A. Mychko, P. Onufrievs



G. Burt, N. Leicester, S. Marks, D. Turner



W. Bradley, S. Simon



R. Berton, D. Piccoli, F. Piccoli, G. Squizzato, F. Telatin

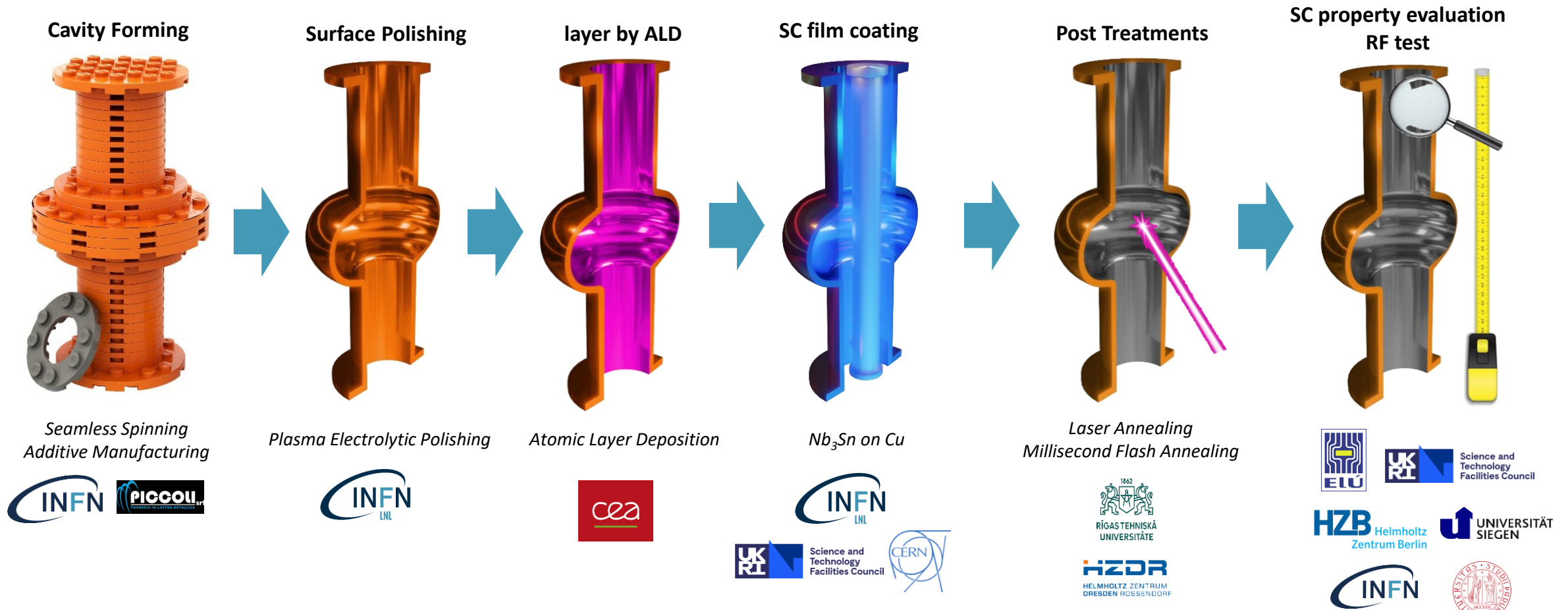
## Associated Partners

 A. M. Valente Feliciano

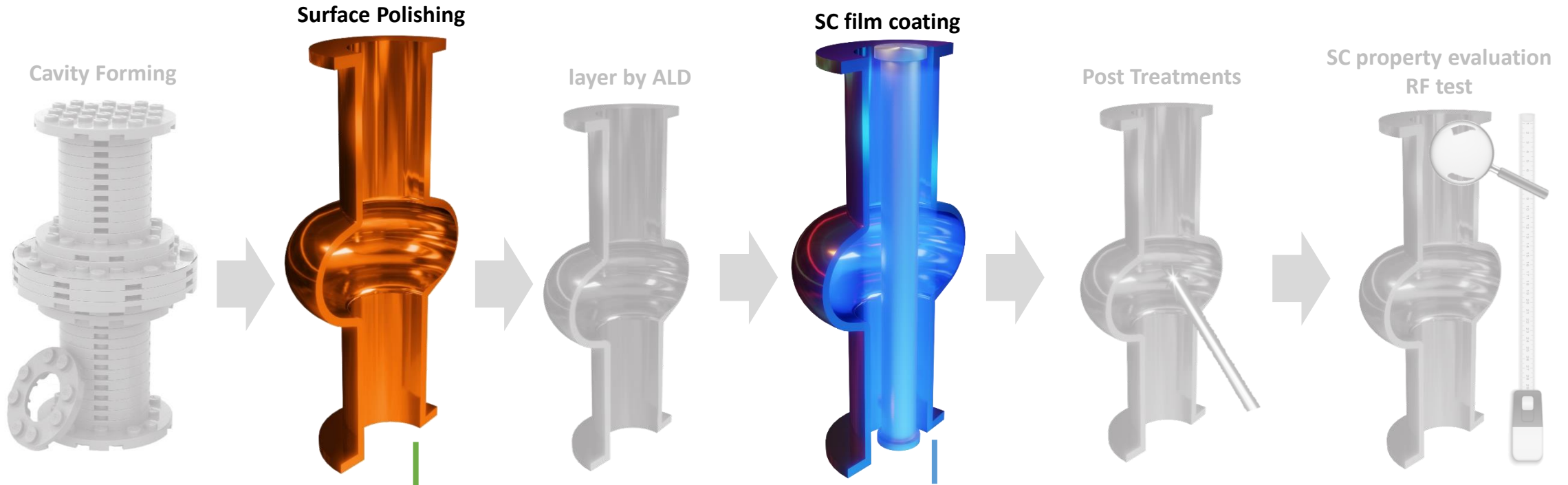
## Informal Partners



# Nb<sub>3</sub>Sn on Cu R&D activity covers all cavity production chain



# Technologies in focus at INFN LNL



Plasma  
Electrolytic  
Polishing



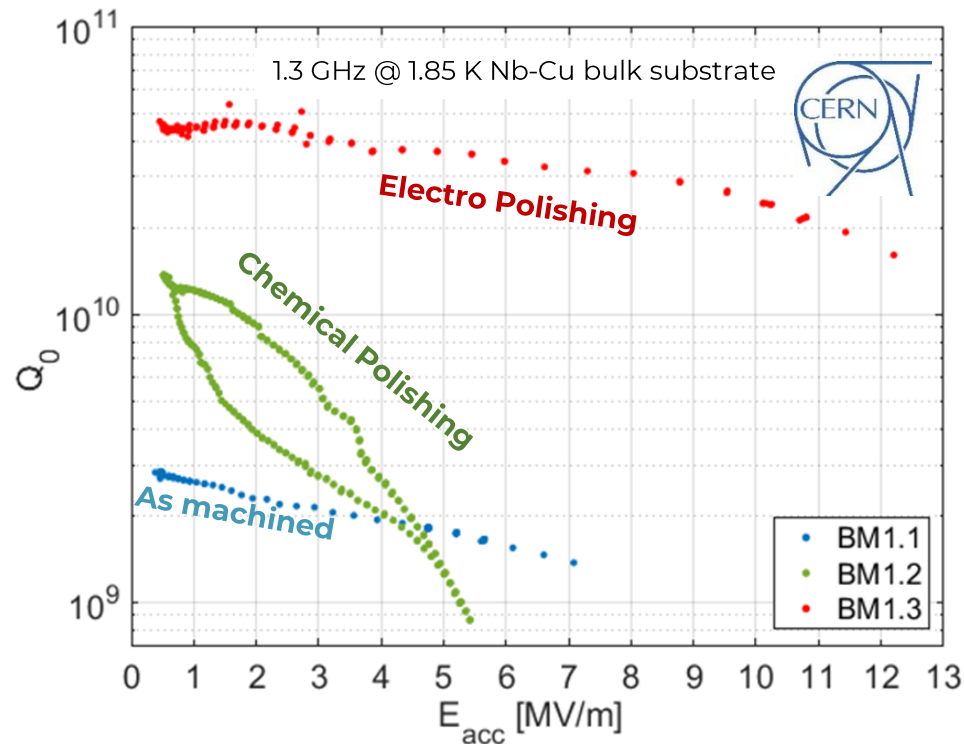
$Nb_3Sn$  on Cu  
Coatings



# Surface Polishing

## PEP

# Surface Polishing



L. Vega Cid, TTC meeting 2022 (elaborated)

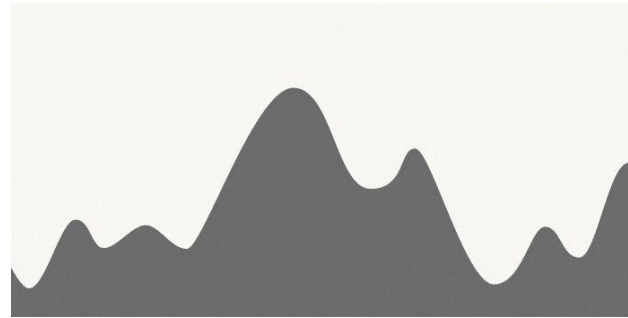
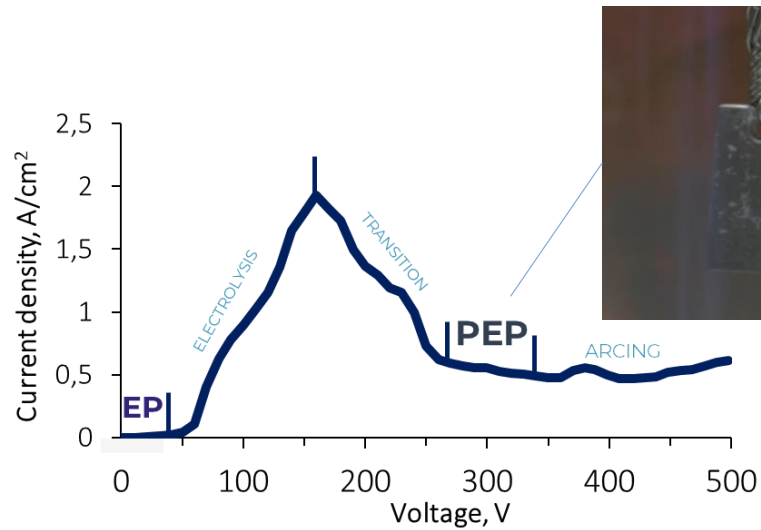
Cu substrate plays a fundamental role in SRF performances

Roughness and defects reduction by **surface treatments are mandatory** for a good and uniform SRF coating

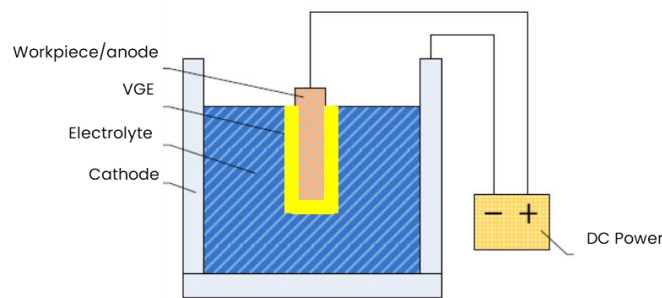
Cavity polishing requires **large amount of acids**. In particular **Nb** requires **HF** (extremely dangerous and poisoning process)



# Plasma Electrolytic Polishing PEP Mechanism



Same EP set-up  
Different regime



J. Wang et al., AMR, 2012

## Advantages



**Green**  
Diluted water solutions,  
environmentally friendly



**Fast**  
The fastest  
non-destructive  
polishing

Equal thickness removal yield  
lowest roughness among  
competitors



**Efficiency**

**Plasma  
Electrolytic  
Polishing**

Less sensitive to the  
cathode shape!  
AM compatible

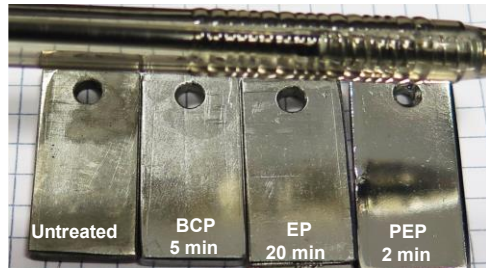
**Versatility**



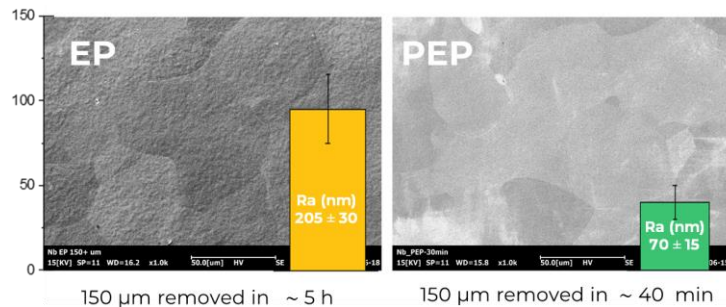
# Plasma Electrolytic Polishing **PEP** Results

1x Nb 3x Cu  
Solution Patents by INFN

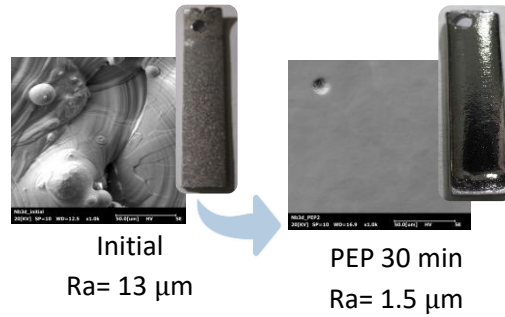
## Planar samples



6.5  $\mu\text{m}$  removed



## Additive Manufacturing



## QPR Samples



**HZB** Helmholtz Zentrum Berlin

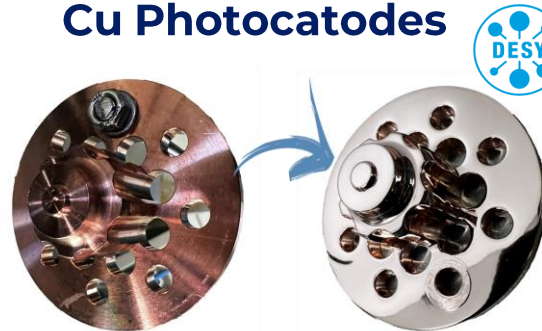
## 6 GHz Cu cavity



### No internal cathode!

70  $\mu\text{m}$  removed in 10 minutes  
30 A (100  $\text{cm}^2 \rightarrow 1.3 \text{ GHz} \sim 300 \text{ A}$ )  
cristian.pira@lnl.infn.it

## Cu Photocathodes



Ra ~ 8 nm!!!



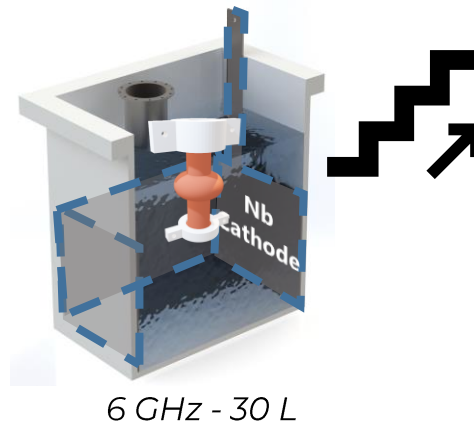
Courtesy of E. Chyhyrnyts

# PEP Path to Final Prototype

*Philosophy: scale 6 GHz set-up to 1.3 GHz converting LNL QWR polishing system*

Priority: test RF performances after PEP

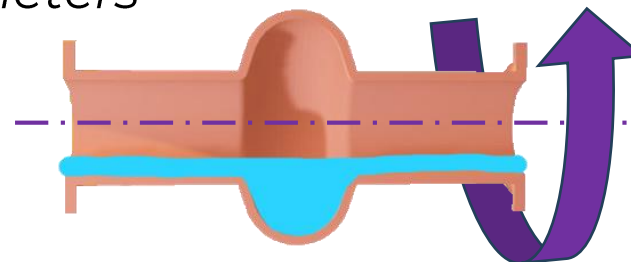
## 1. Simpler set-up: cavity fully immersed



1.3 GHz - 300 L

## 2. Alternative set-up to Reduce Process Power

- *Reduce Treated Area (rotating cavity)*
- *Optimizing Process Parameters (Temperature, Voltage, ...)*



QWR Implant @LNL

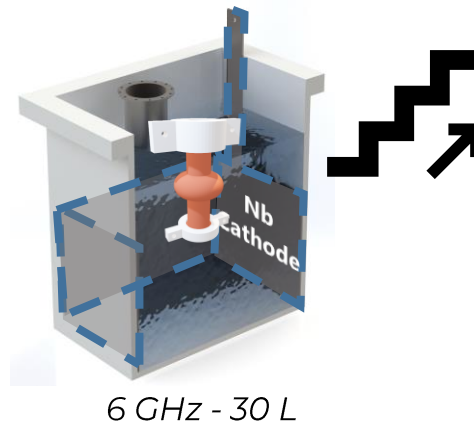
cristian.pira@lnl.infn.it



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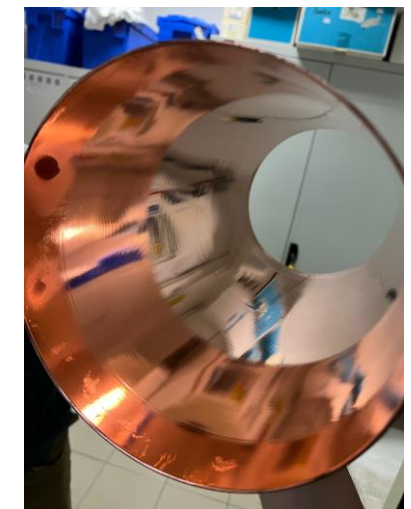
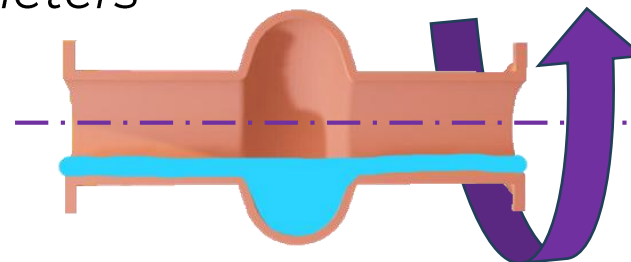


1.3 GHz - 300 L

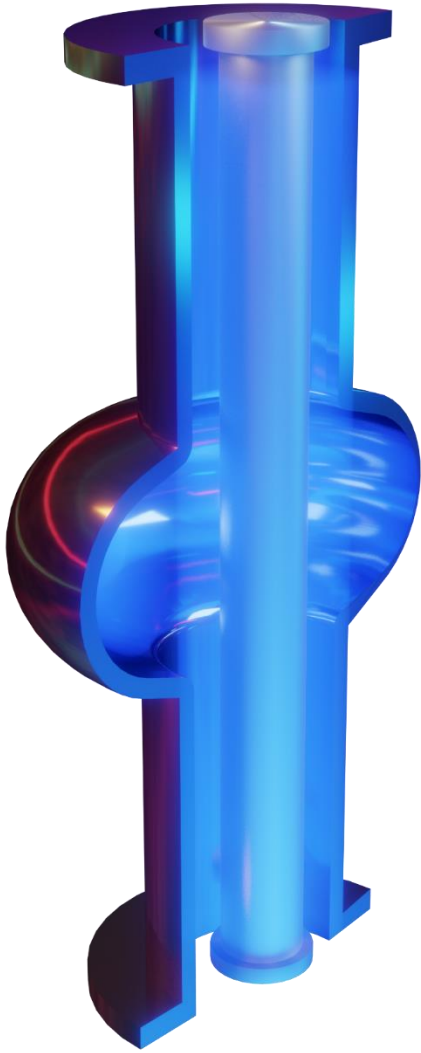
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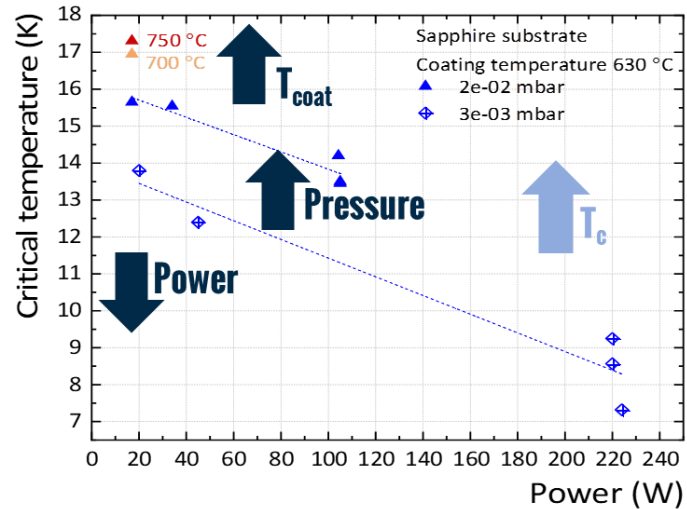
2300 cm<sup>2</sup> tube treated by PEP (150 A,  
cristian.pira@lnl.infn.it



# $Nb_3Sn$ on Cu Coatings

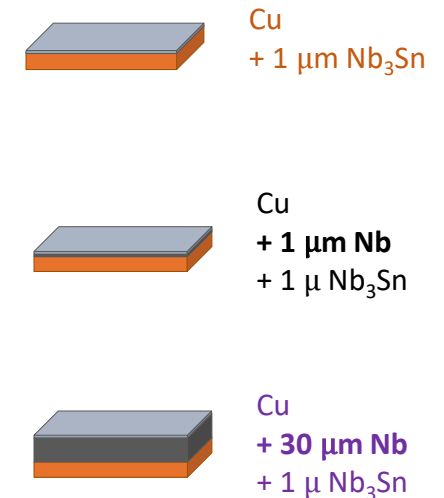
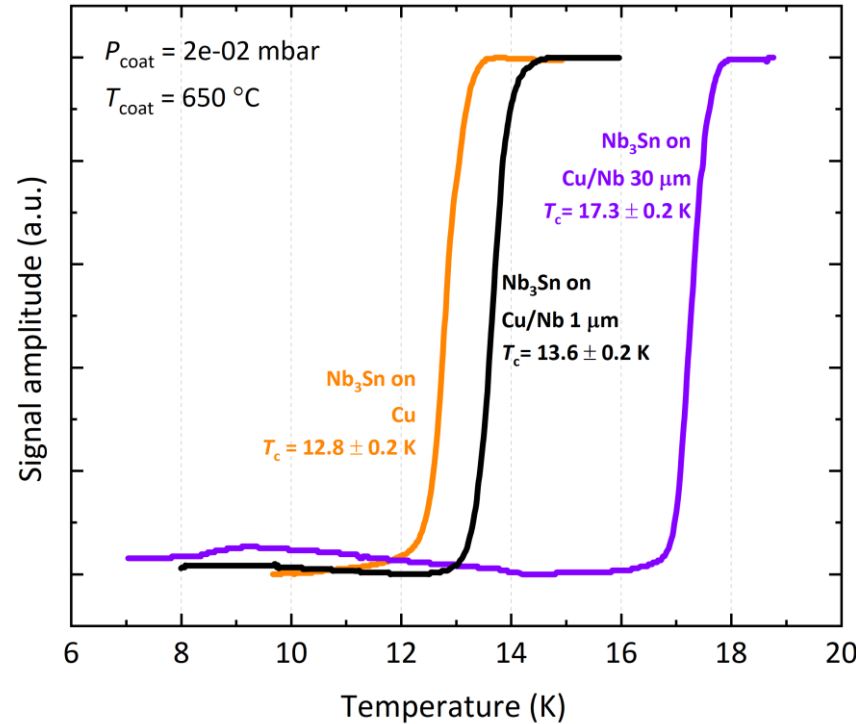
# Nb<sub>3</sub>Sn Coatings

Long R&D phase on PVD Parameter Optimization



## Optimized Coating Recipe

- Coating Parameters:
  - Pressure =  $2 \cdot 10^{-2}$  mbar
  - Power = 16 W
  - T substrate  $\geq 600$  C
- Nb Thick Barrier Layer > 30  $\mu$ m**



**A thick Nb buffer layer accommodates the Nb<sub>3</sub>Sn coating**

**Nb substrate can be used to validate Nb<sub>3</sub>Sn Coating Performances**

# First Nb<sub>3</sub>Sn RF Results

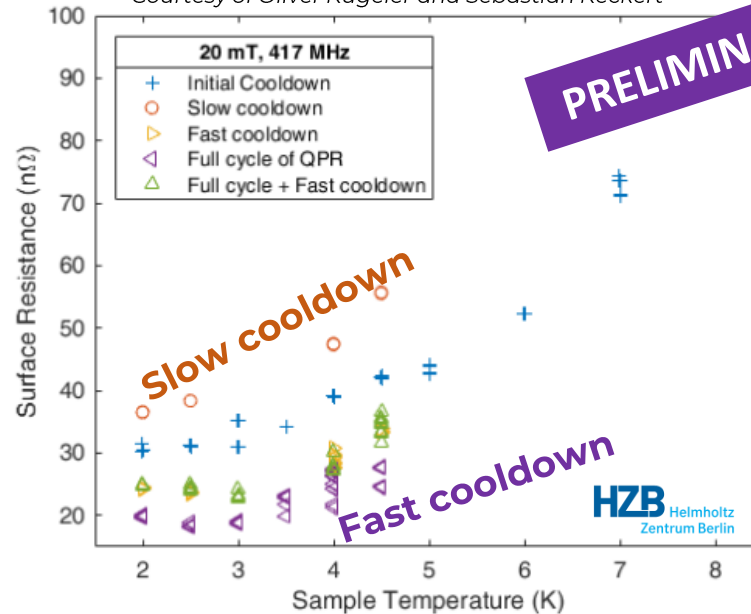
## (on a small Nb planar resonator)



Rs of 23 nΩ @ 4.5 K, 20 mT  
 Quench >70 mT @ 4.5 K

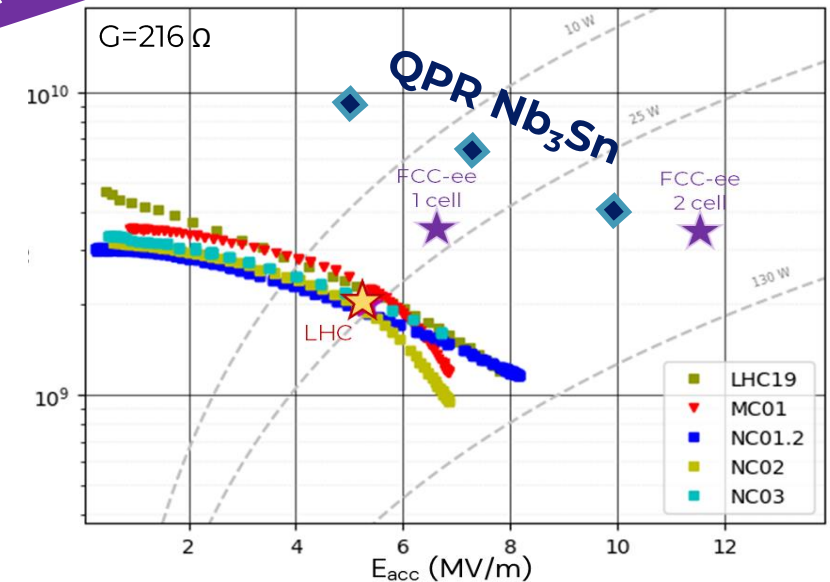
- ▶ Nb<sub>3</sub>Sn coating suffer flux trapping
- ▶ Cooldown procedure influence Rs

Courtesy of Oliver Kugeler and Sebastian Keckert



PRELIMINARY RESULTS

LHC cavities Q vs E<sub>acc</sub> @4.5 K



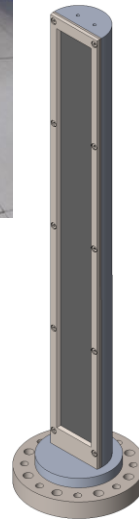
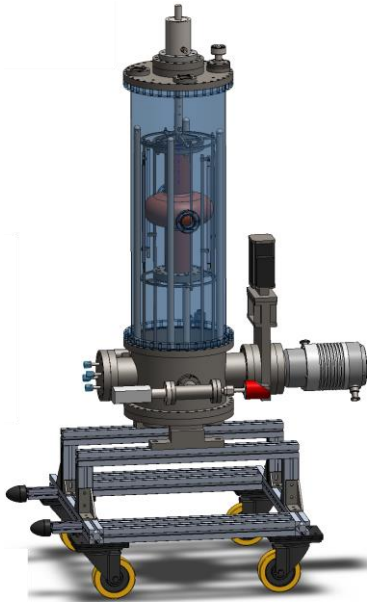
Equivalent to a Q of 9·10<sup>9</sup> @5 MV/m @4.5 K  
 5 times better than LHC → FCC-ee compatible  
 Room for improvement

# Nb<sub>3</sub>Sn Path to Final Prototype

Nb<sub>3</sub>Sn on bulk Nb to validate coating performances (2025)  
on 1.3 GHz Elliptical Cavities (2025)

Develop Nb thick barrier/accommodation layer on 1.3 GHz Elliptical Cavities (2025)  
(proof of concept on 6 GHz cavities already done)

Nb<sub>3</sub>Sn on Cu with thick Nb coating on 1.3 GHz Elliptical Cavities (2026-2028)



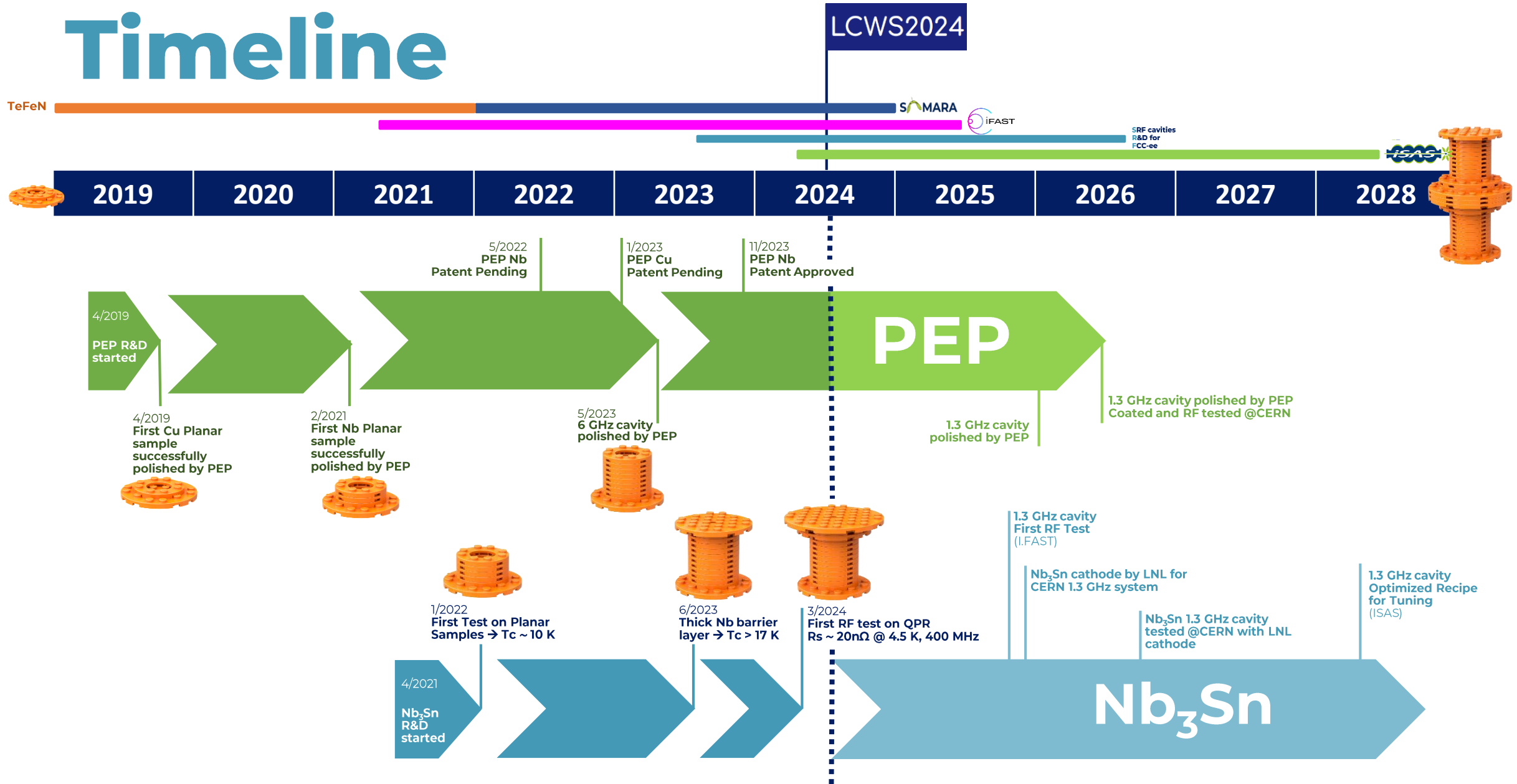
- ▶ 1.3 GHz Vacuum system ready
- ▶ Magnetron source commissioned

*In parallel:*

- ▶ Study on alternative buffer layer
- ▶ Study on flux trapping



# Timeline



# Conclusion

- ▶ **PEP and Nb<sub>3</sub>Sn films** are possible **game changer technologies** for SRF accelerating cavities
- ▶ **Big steps forward** in the last two years with transition from planar to 3D samples
- ▶ **Very promising results from first RF test**
- ▶ **Validation with 1.3 GHz cavities is necessary** prior to evaluating the feasibility of implementing these technologies in real accelerators
- ▶ **End of 2025** we expect to have the **first tests** available on **1.3 GHz cavities**
- ▶ **In 2028 optimized prototypes** are expected



Work supported by INFN CSN5 experiment SAMARA and INFN CSN1 experiments SRF and RD\_FCC

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# Thank you!

Giovanni  
Marconato

Davide  
Ford

Eduard  
Chyhrynets

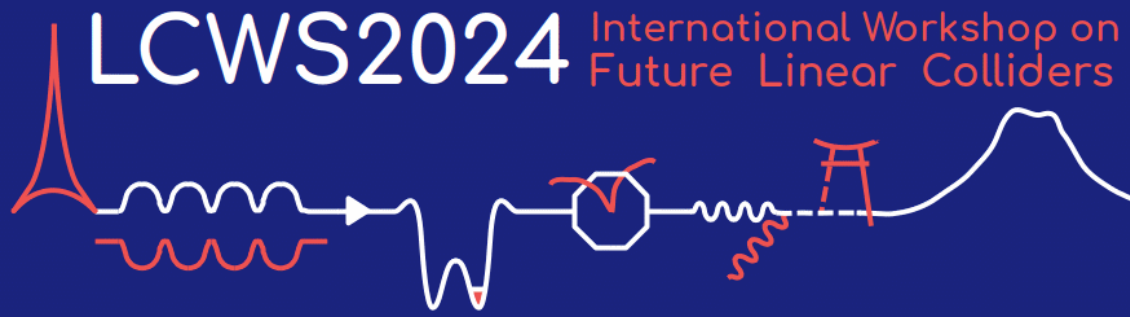
Cristian  
Pira

Dorothea  
Fonnesu

Roberta  
Caforio

Alessandro  
Salmaso





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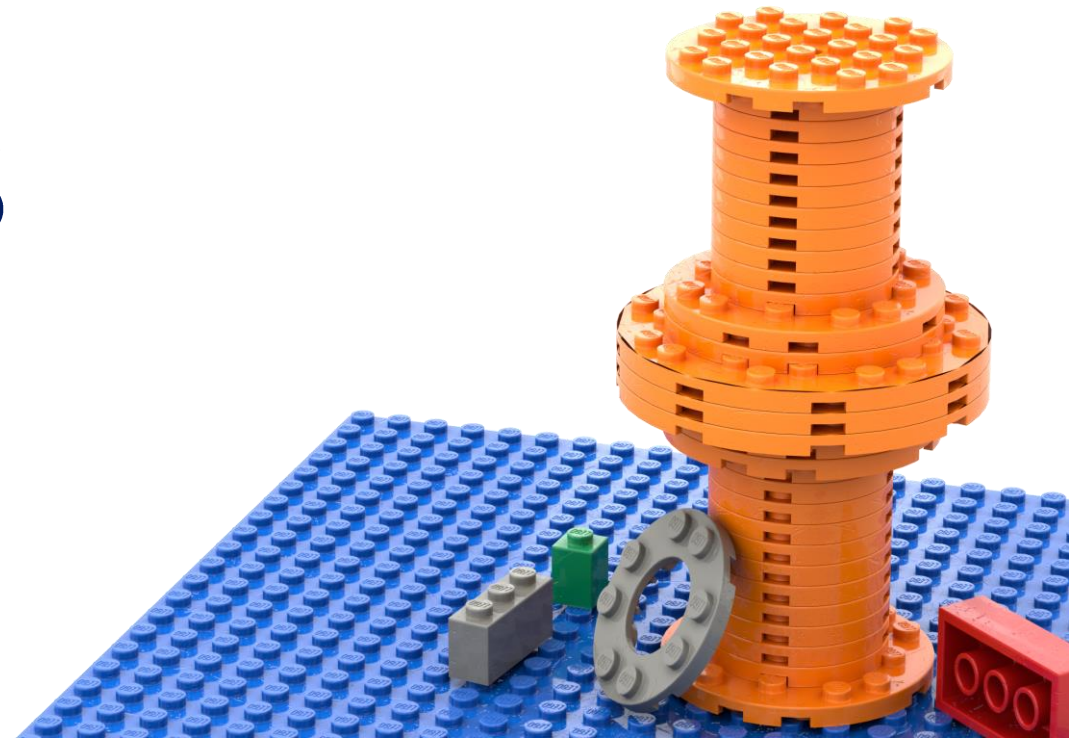
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# Backup Slides



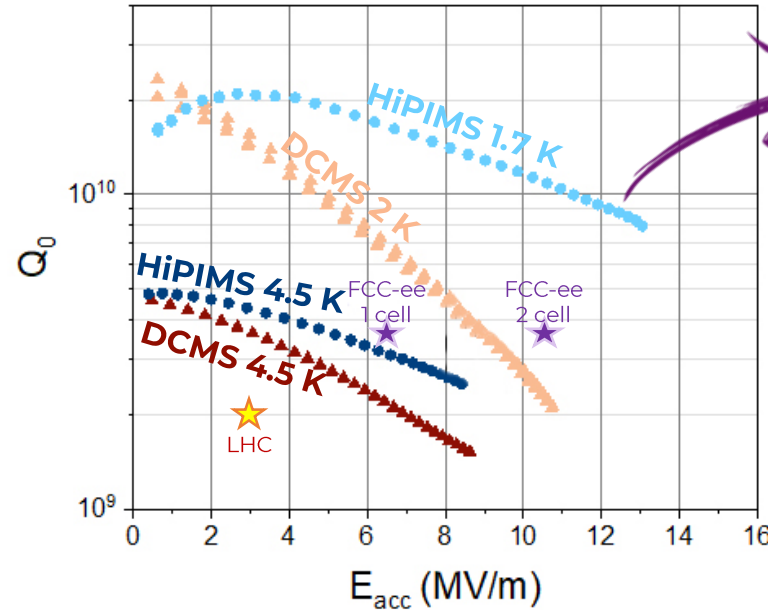
# Nb<sub>3</sub>Sn motivation

**Energy saving** is mandatory for **FCC-ee** and the **next generation accelerators**...

...**cryogenics** is one of the **larger energy cost** in modern SRF accelerators

Move from thin film Nb @4.5 K to Nb<sub>3</sub>Sn @4.5 K

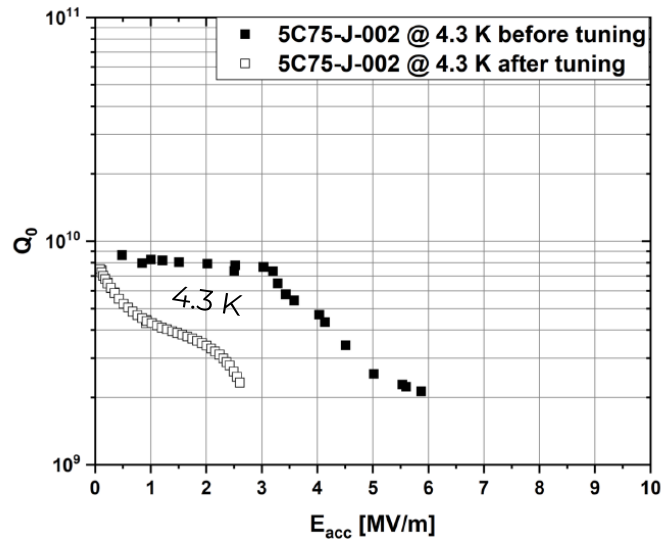
Reduce  $T_{op}/T_c \rightarrow$  Suppress  $R_{BCS} \rightarrow$  Increase  $Q$



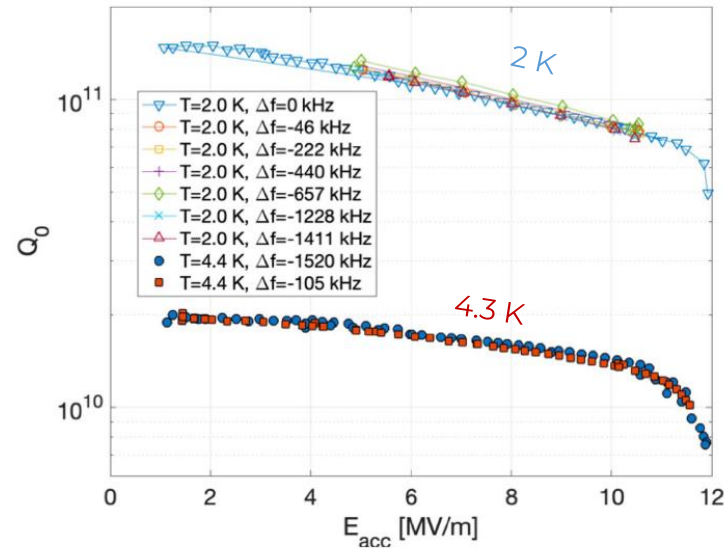
Expected Performances for Nb<sub>3</sub>Sn

Carlota Pereira Carlos, FCC week 2023 (elaborated)

# Cavity Tunability



**Strong performance degradation** after **room temperature** tuning for 200 kHz



**Little change** in the coated cavity performance after tuning up to 1400 kHz at **cryogenic temperatures**

## Nb<sub>3</sub>Sn is extremely brittle

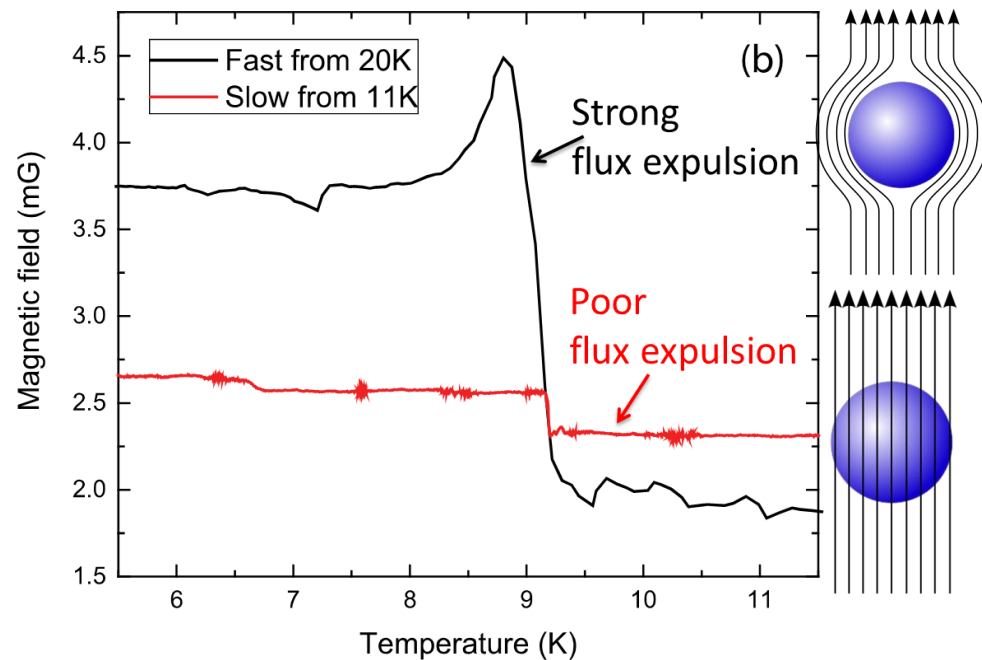
Eremeev, G. (2023). Tunability/robustness of Nb<sub>3</sub>Sn (No. FERMILAB-SLIDES-23-402-TD). Fermi National Accelerator Laboratory (FNAL), Batavia, IL (United States).

- ▶ **Vapor Tin Diffusion Nb<sub>3</sub>Sn on Nb cavities can be tuned only at cryogenic T**
- ▶ **An interlayer in Nb<sub>3</sub>Sn on Cu coatings can be added to enhance film mechanical stability and tunability**

# Trapped Flux

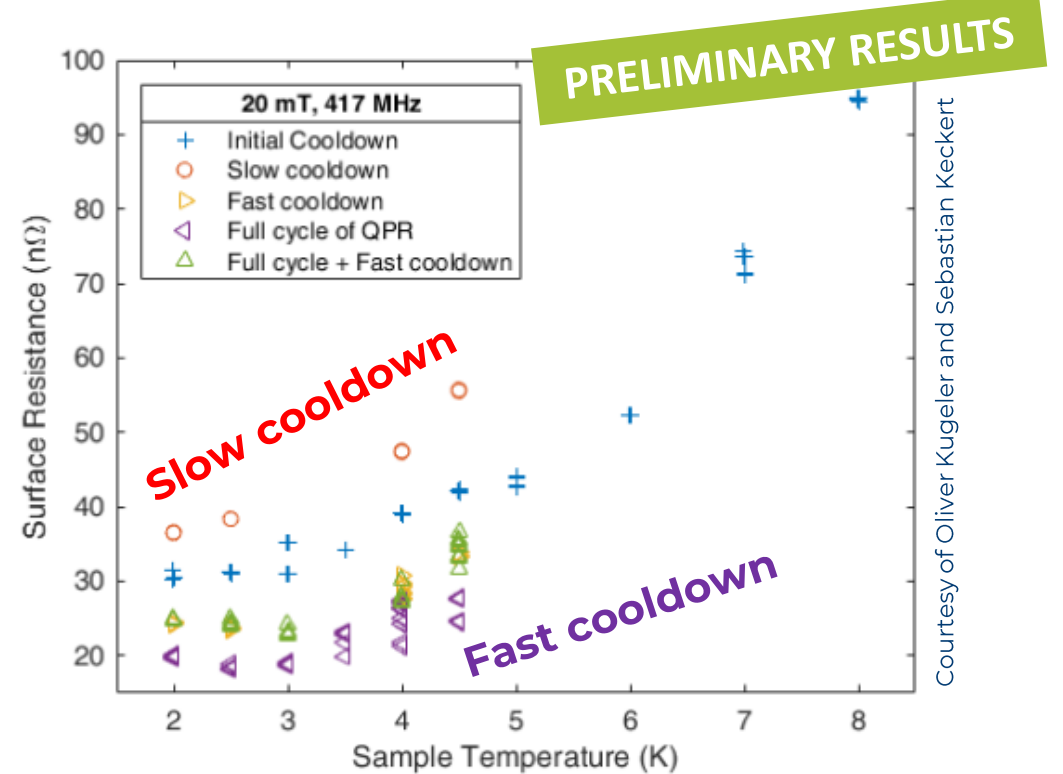
$$Q_0 \propto \frac{1}{R_{BCS} + R_{res} + \eta S B}$$

Fraction of Trapped Flux      Sensitivity



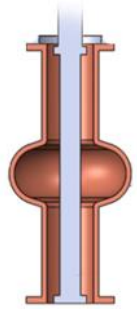
A. Romanenko, A. Grassellino, O. Melnychuk, D. A. Sergatskov, *J. Appl. Phys.* 115, 184903 (2014)

## First ISAS Results:



- ▶ **Nb<sub>3</sub>Sn coating suffer flux trapping**
- ▶ **Cooldown procedure influence Rs**

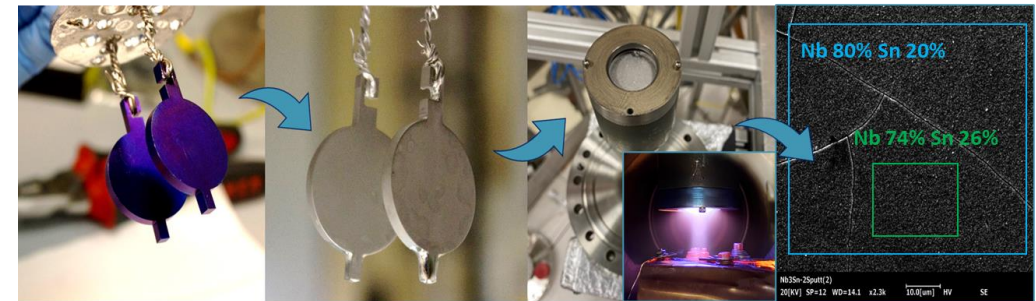
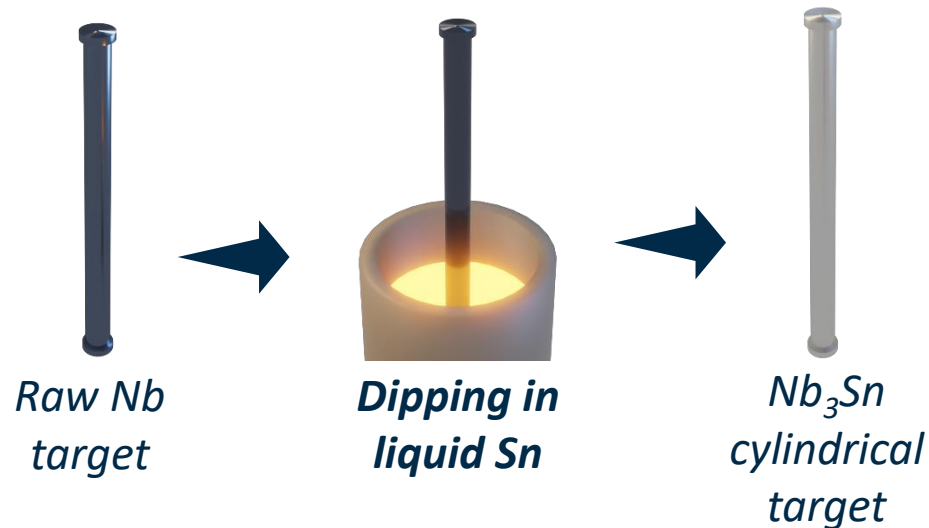
# Nb<sub>3</sub>Sn coatings: target production



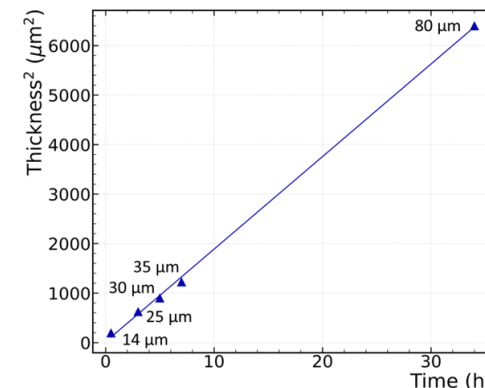
Single target configuration **easiest to scale** onto elliptical geometry

Nb<sub>3</sub>Sn cylindrical targets are not commercially available

**LNL Strategy for Nb<sub>3</sub>Sn cylindrical targets production for 6 GHz cavities**



Proof of concept

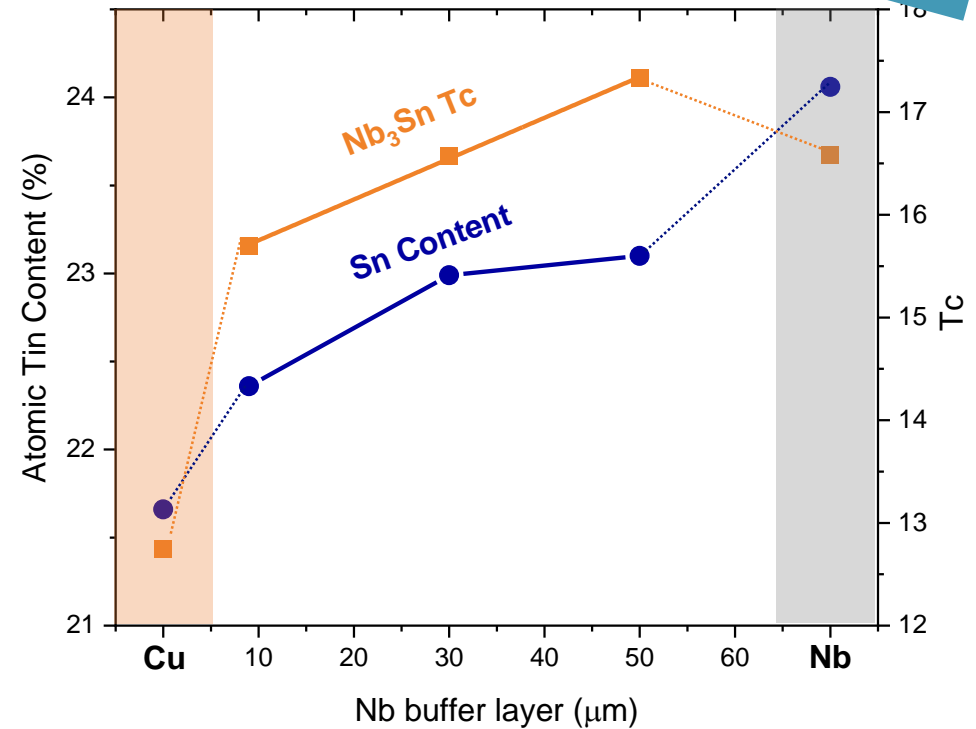
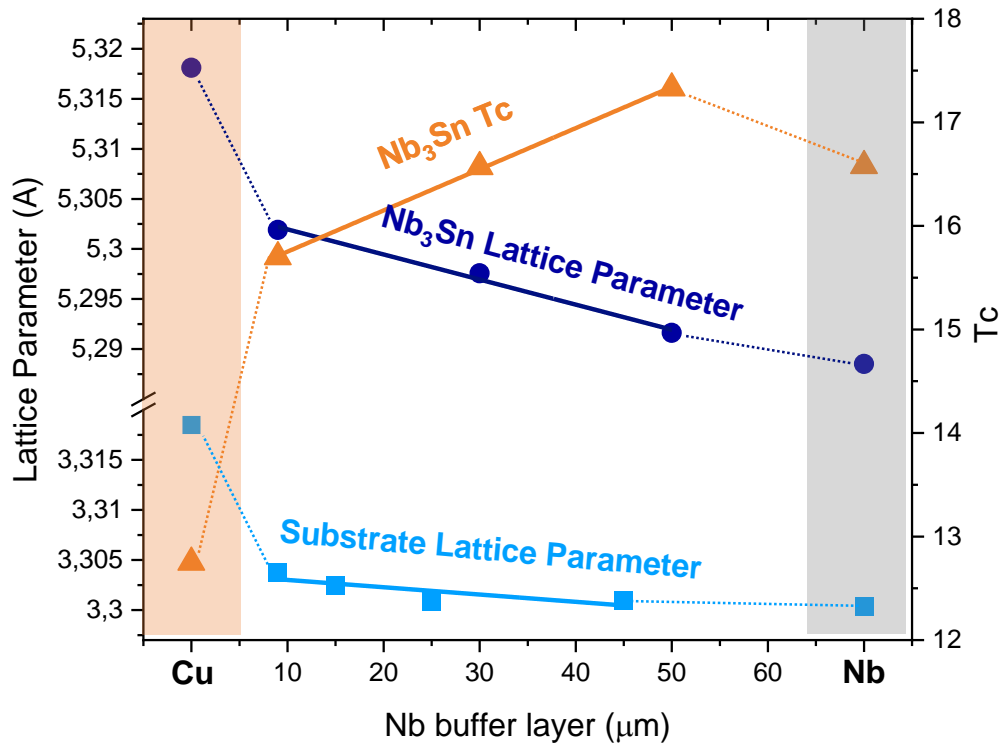


Nb<sub>3</sub>Sn **thickness** related to **dipping time**

Possible **tin content modulation**

# Nb<sub>3</sub>Sn coatings

## Sputtering parameter optimization



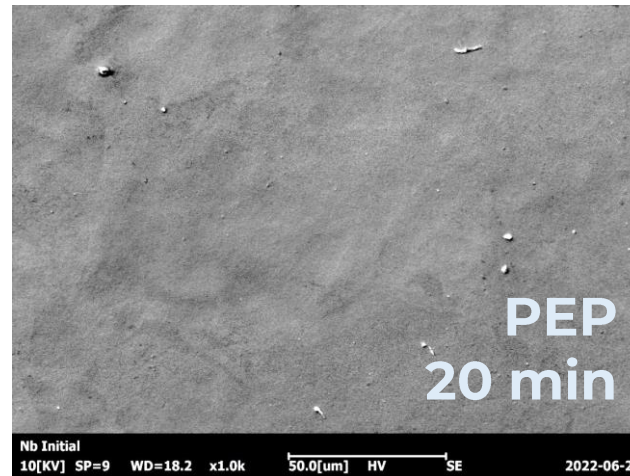
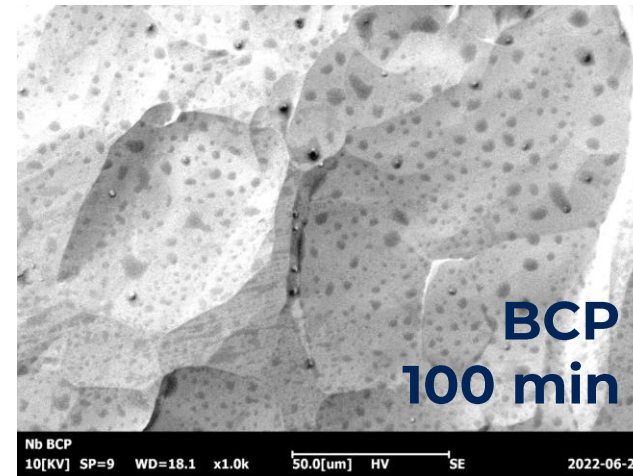
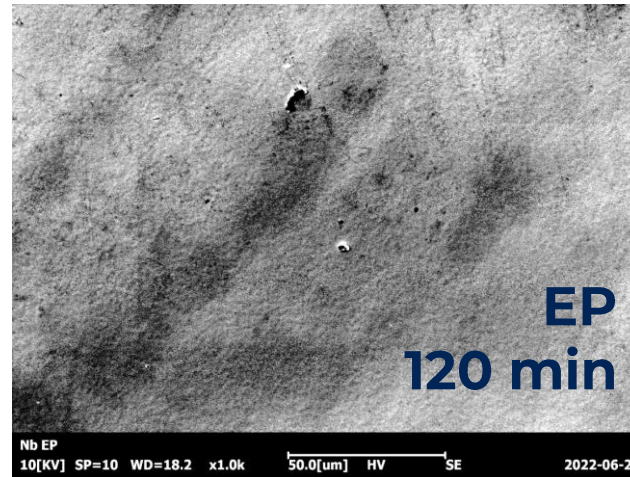
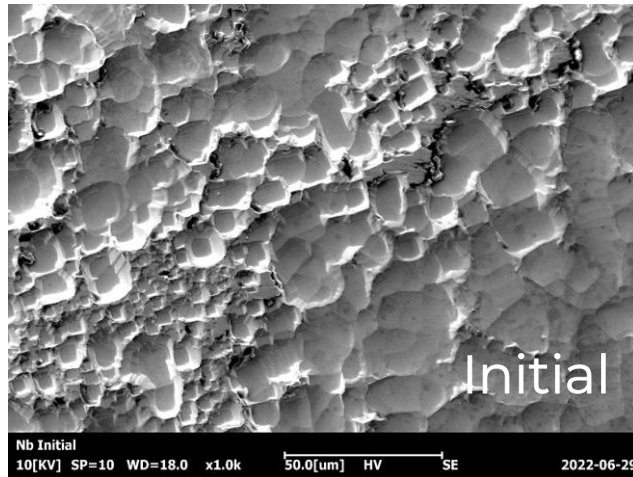
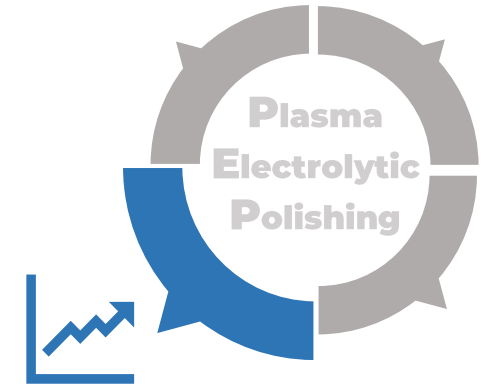
The role of the thick Nb layer is to accommodate the Nb<sub>3</sub>Sn lattice parameter



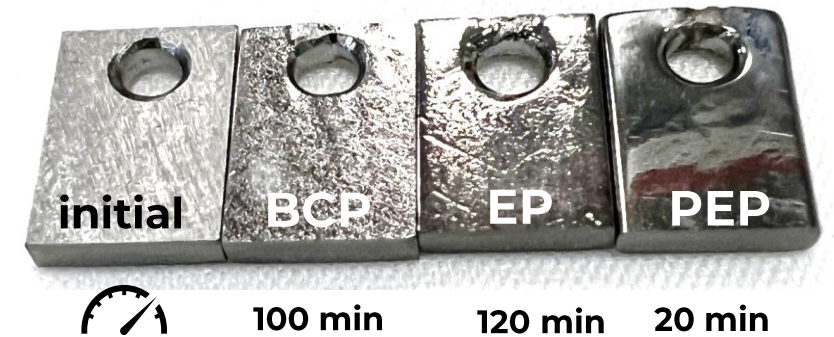
ALD layer could be an alternative to explore

# PEP is Efficient

## Comparison with EP and BCP



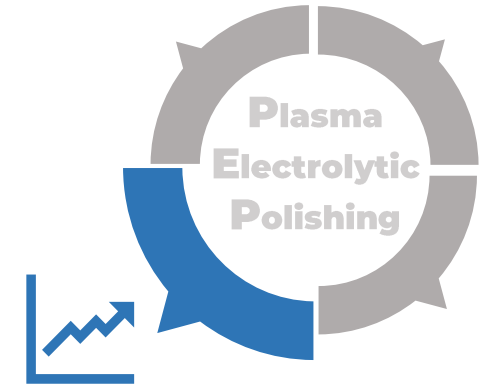
Nb, Magnification **1000x**;  
100  $\mu\text{m}$  Removal



Both micro and macro  
**roughness is improved significantly**

# PEP is Efficient

## Comparison with EP and BCP



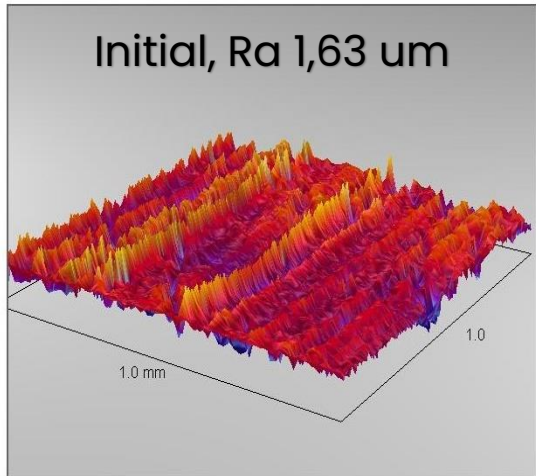
Dektak 8

Surface Stats:

Ra: 1.63  $\mu\text{m}$   
Rq: 2.11  $\mu\text{m}$   
Rt: 16.92  $\mu\text{m}$

Measurement Info:

Sampling: 222.22 nm  
Array Size: 4500 X 315



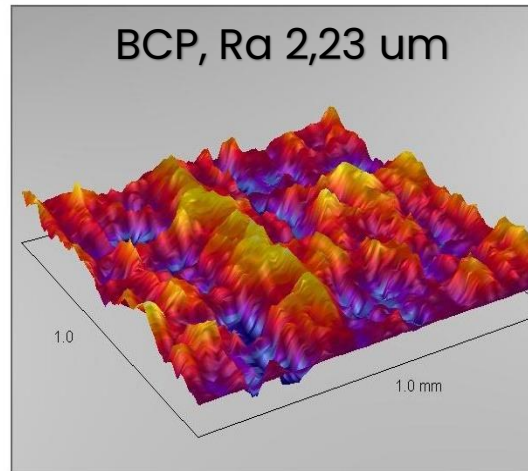
Dektak 8

Surface Stats:

Ra: 2.23  $\mu\text{m}$   
Rq: 2.73  $\mu\text{m}$   
Rt: 5.02  $\mu\text{m}$

Measurement Info:

Sampling: 222.22 nm  
Array Size: 4500 X 316



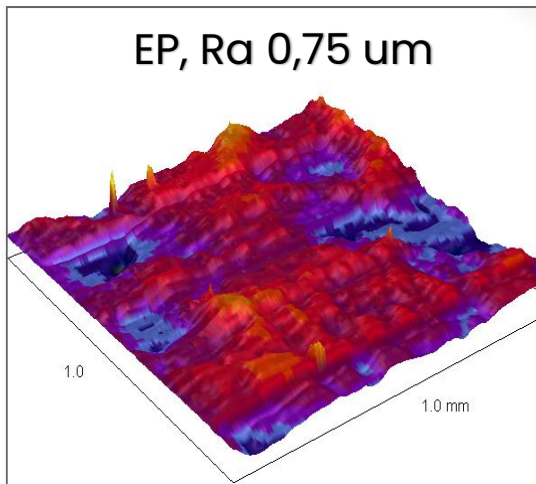
Dektak 8

Surface Stats:

Ra: 750.04 nm  
Rq: 927.93 nm  
Rt: 7.81  $\mu\text{m}$

Measurement Info:

Sampling: 333.33 nm  
Array Size: 3000 X 316



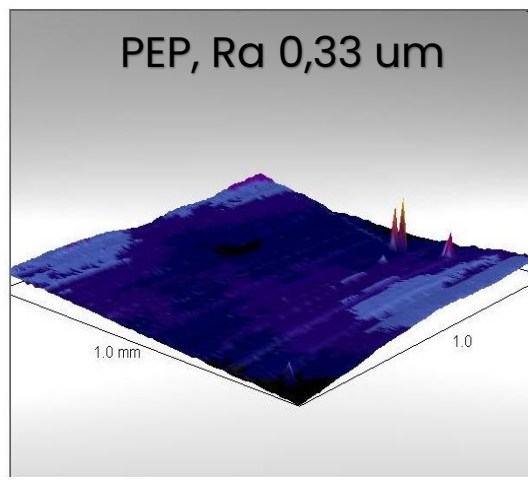
Dektak 8

Surface Stats:

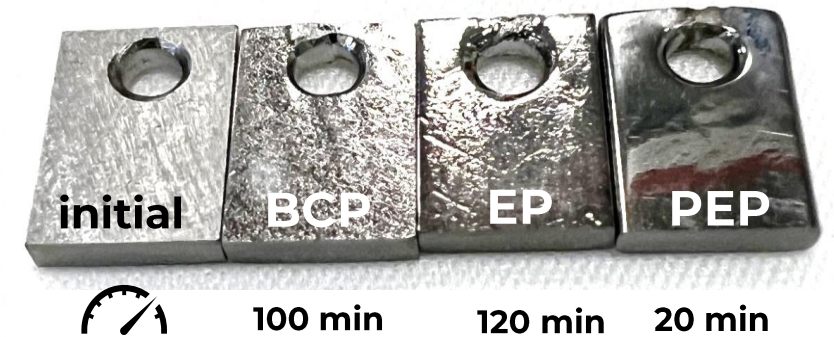
Ra: 0.33  $\mu\text{m}$   
Rq: 0.42  $\mu\text{m}$   
Rt: 1.18  $\mu\text{m}$

Measurement Info:

Sampling: 222.22 nm  
Array Size: 4500 X 316



Nb, Magnification **1000x**;  
100  $\mu\text{m}$  Removal



Both micro and macro  
**roughness is improved significantly**

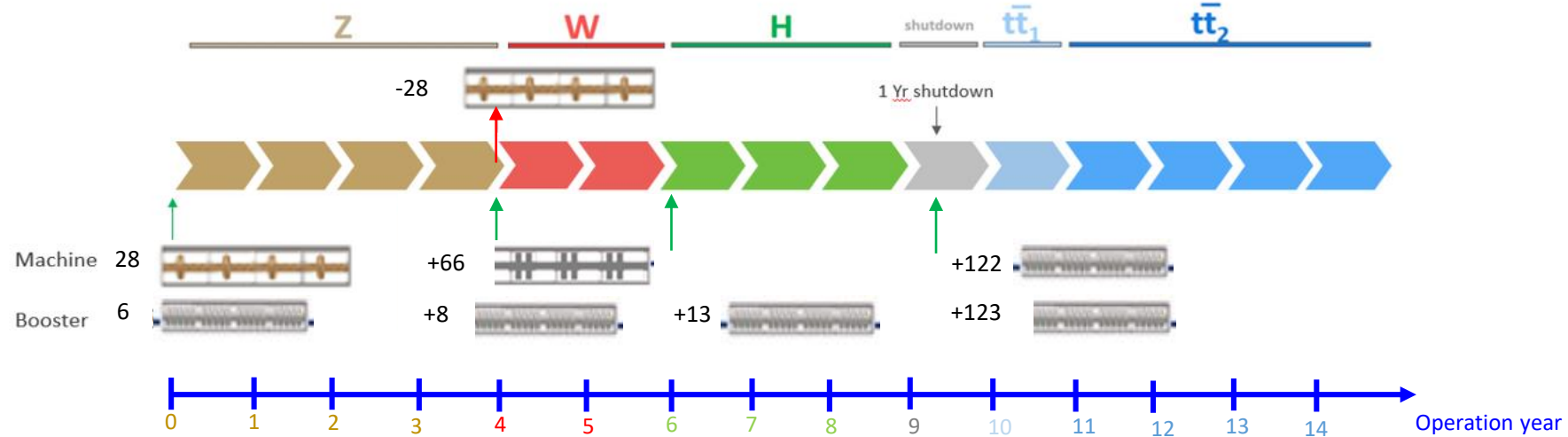


# Comparison

## Copper treatments

Process / parameters	"SUBU5"	EP (3:2)	PEP in "SUBU5"
Solution composition	Sulfamic acid 5 g/l; NH <sub>4</sub> -citrate 1 g/l Butanol 50 ml/l; H <sub>2</sub> O <sub>2</sub> 50 ml/l	85 % H <sub>3</sub> PO <sub>4</sub> 60 p. 99% n-Butanol 40p.	Sulfamic acid 5 g/l; NH <sub>4</sub> -citrate 1 g/l Butanol 50 ml/l; H <sub>2</sub> O <sub>2</sub> 50 ml/l
Voltage	-	2-6 V	300 V
Current density	-	0,01 – 0,03 A/cm <sup>2</sup>	0,25-0,8 A/cm <sup>2</sup>
Power draw	-	0,06 – 0,18 W/cm <sup>2</sup>	75 – 240 W/cm <sup>2</sup>
Removing rate	1,5 μm/min (70±2 °C)	0,15-0,5 μm/min (25 °C)	20-30 μm/min (80 °C)

# SRF System Baseline for FCC



**In total: 366 CM, 1'464 cavities (4 cavities/CM, present assumption):**

- ▶ 400 MHz single-cell (Nb/Cu): 28 CM, 112 cavities → 4.5 K (to be removed after Z)
- ▶ 400 MHz two-cell (Nb/Cu): 66 CM, 264 cavities → 4.5 K
- ▶ 800 MHz five-cell (bulk Nb): 272 CM, 1'088 cavities → 2 K

**Collider** (ttbar2): 188 CM (264 cavities 400 MHz, 488 cavities 800 MHz)

**Booster** (ttbar2): 150 CM (600 cavities 800 MHz)

**Performance of thin film 400 MHz are one of the main challenges of FCC SRF System**

SRF System Baseline from Vittorio Parma, FCC week 2023

# 400 MHz requirements

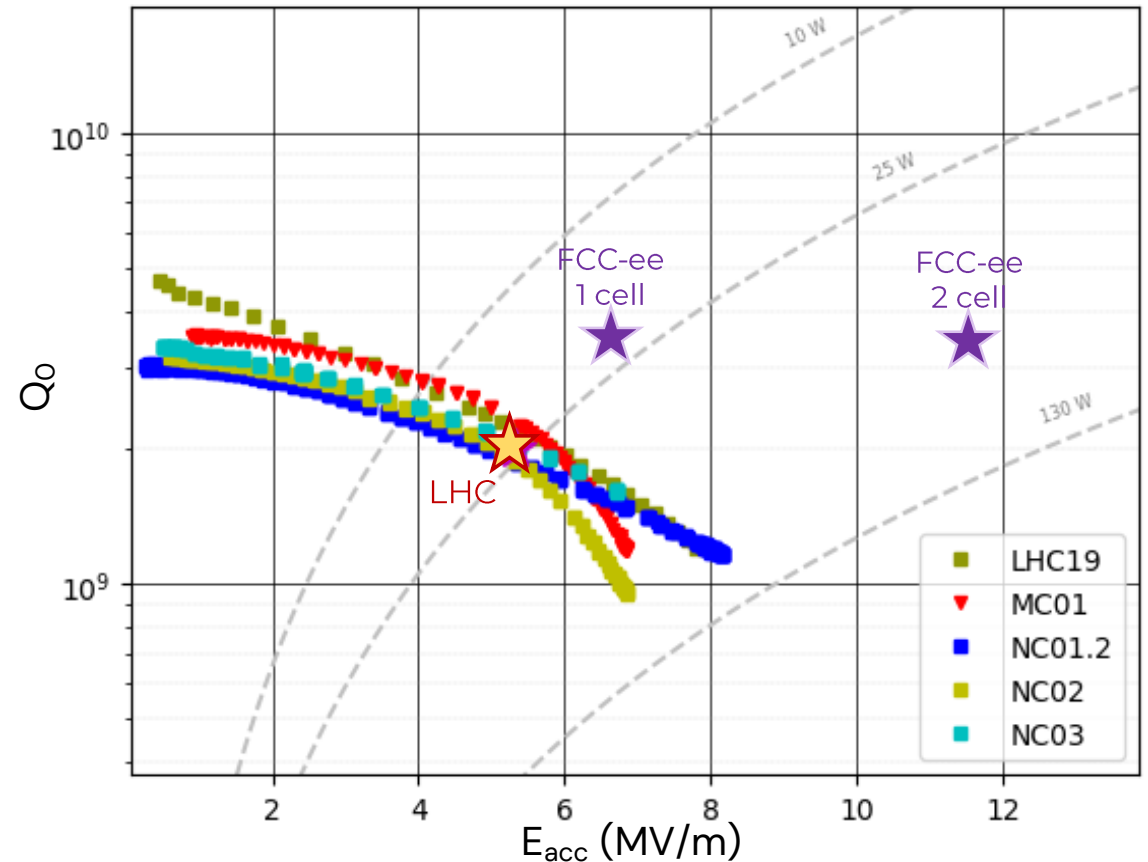


**FCC-ee** requires higher cavities performances than LHC

*Nb on Cu "baseline", Solid scheme with good margin for reliable operation Clear R&D paths identified (seamless copper cavities, HiPIMS coating, High Q0 bulk Nb cavities)*

Franck Peauger, FCC week 2023

LHC cavities Q vs  $E_{acc}$  @4.5 K

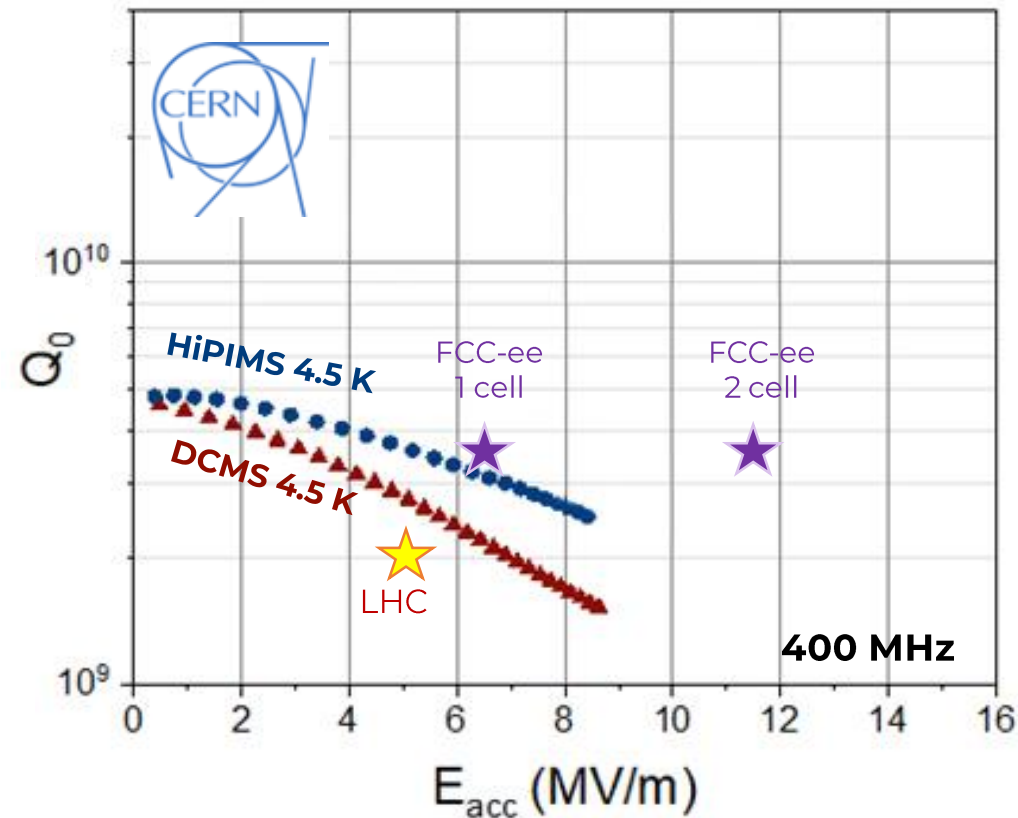
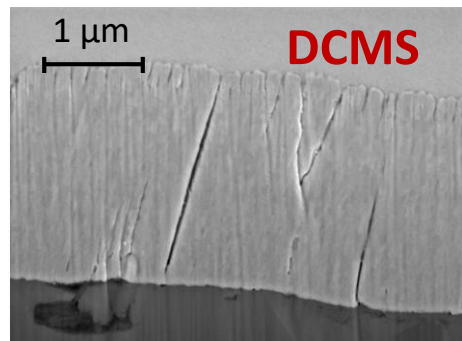
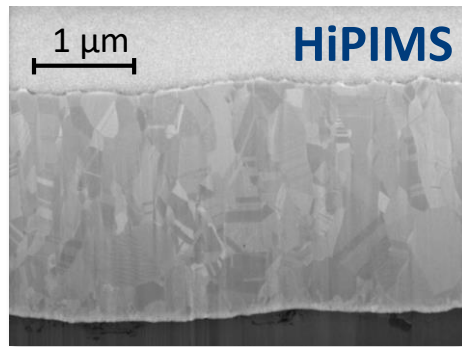


Graph from Carlota Pereira Carlos, FCC week 2023

# SRF R&D @CERN for FCC

## HiPIMS technology densifies the Nb coating and increases RF performances compared to DCMS

Carlota Pereira Carlos, FCC week 2023 (elaborated)



R&D @CERN also on cavity forming (hydroforming), polishing (EP), Cu oxide layer, Nb<sub>3</sub>Sn by HiPIMS